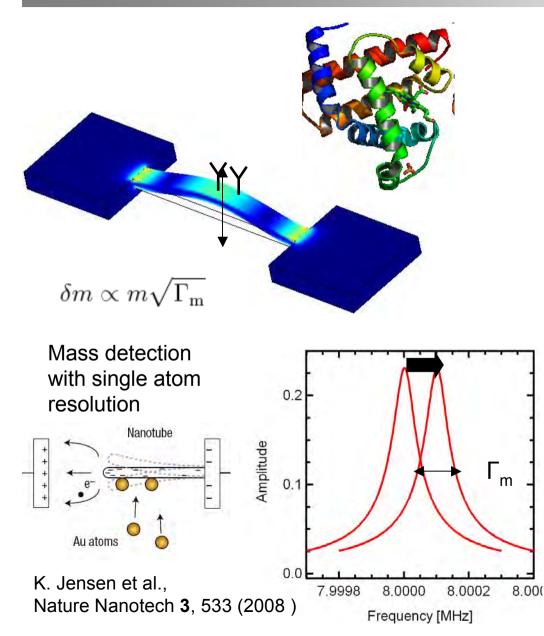
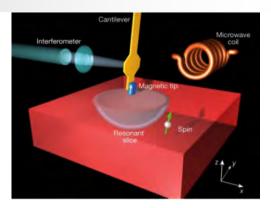


Why NanoElectroMechanical Systems (NEMS)? Sensing of masses, forces, displacements

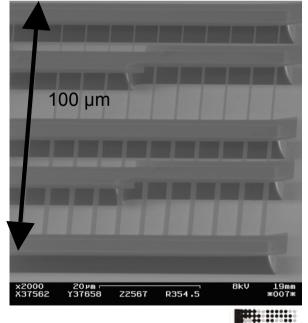


 $\delta F \propto \sqrt{m\Gamma_{\rm m}}$

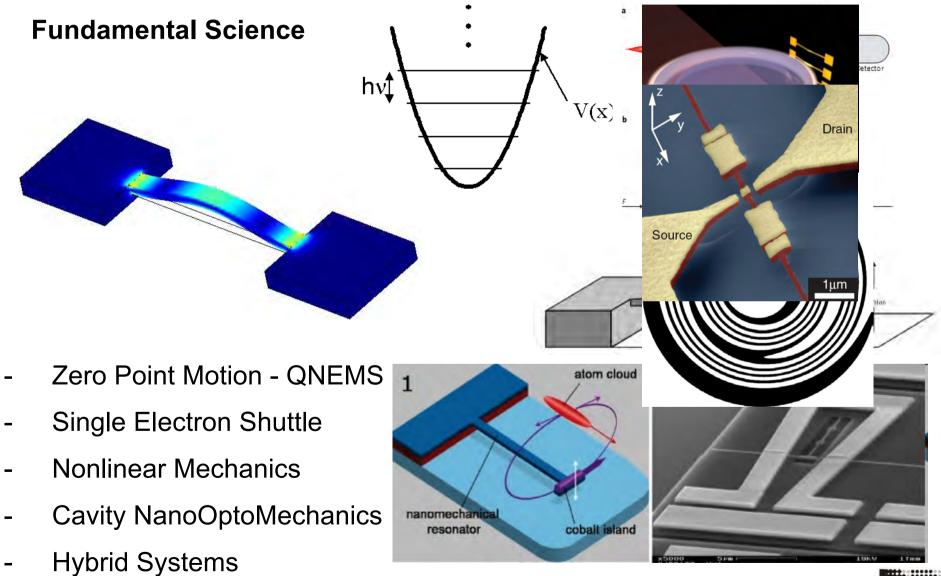


Force sensing with single spin sensitivity D. Rugar et al., Nature, **430**, 329 (2004)

Highly scalable here:10⁴/mm²



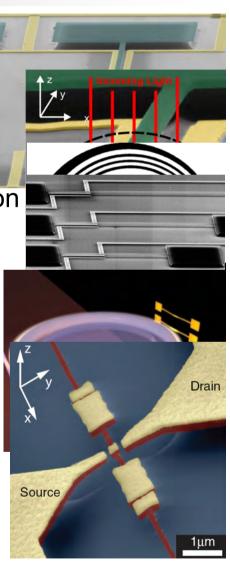
Why NanoElectroMechanical Systems (NEMS)? Some fundamental science problems





Outline

- Actuation by electrical gradient fields
- Detection on-chip interferometric and self-oscillation
- Non-linear behavior and induced switching
- Damping and mechanical quality factor
- Optical gradient field actuation and
- Quantum limited detection
- Shuttling charge with NEMS





On-chip electrical gradient force transduction

in collaboration with

Quirin Unterreithmeier Thomas Faust

Eva M. Weig



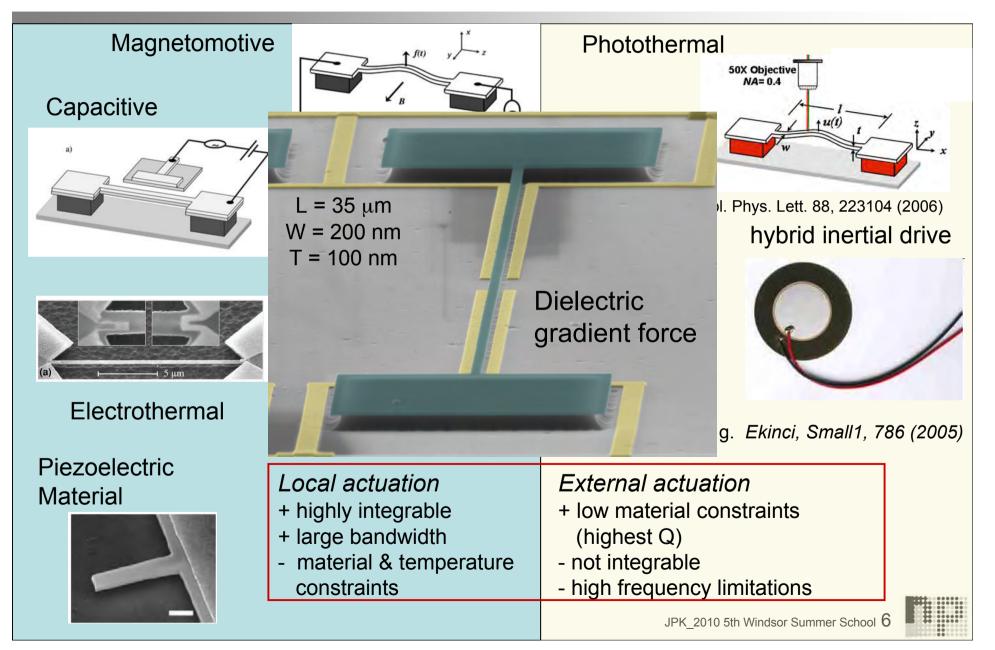




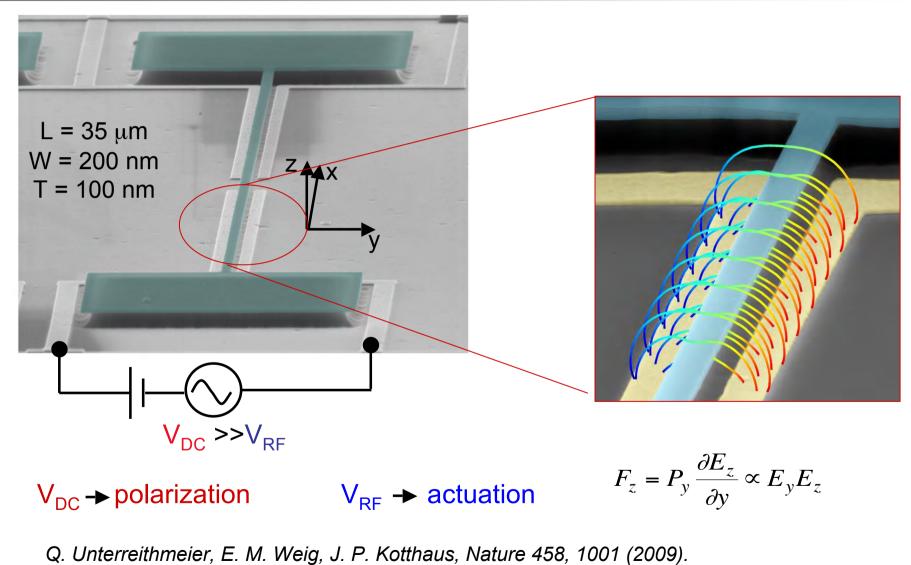


Actuating nanomechanical resonators

The pros and cons of common schemes



The principle of dielectric actuation via a gradient force A polarizable body subject to a gradient field will experience a force

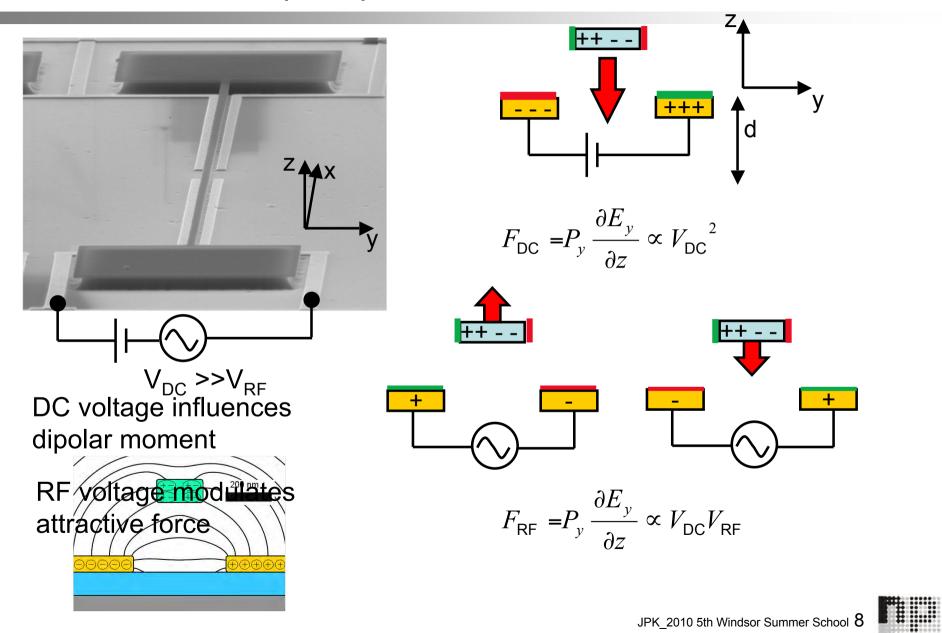


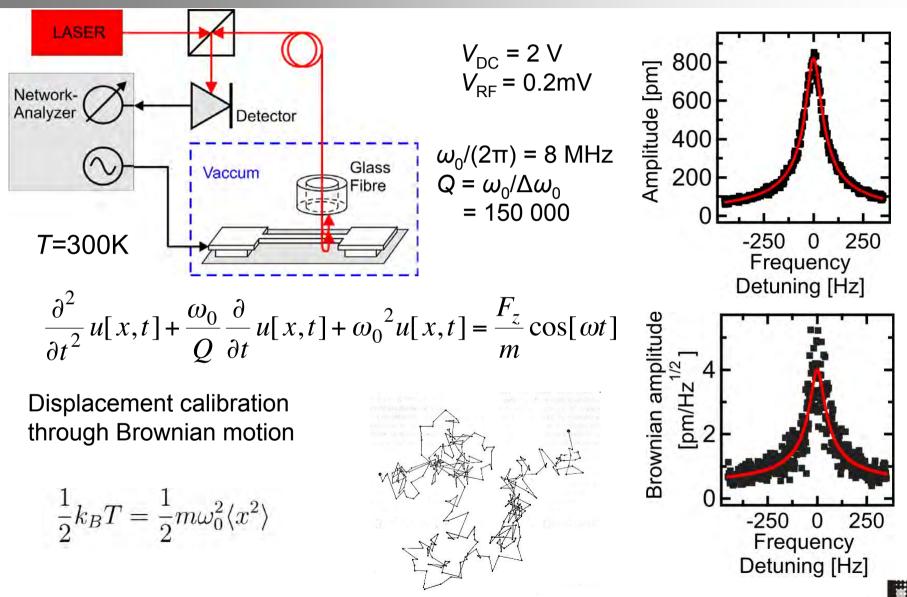
see also: S. Schmid et al., Appl. Phys. Lett. 89, 163506 (2006)

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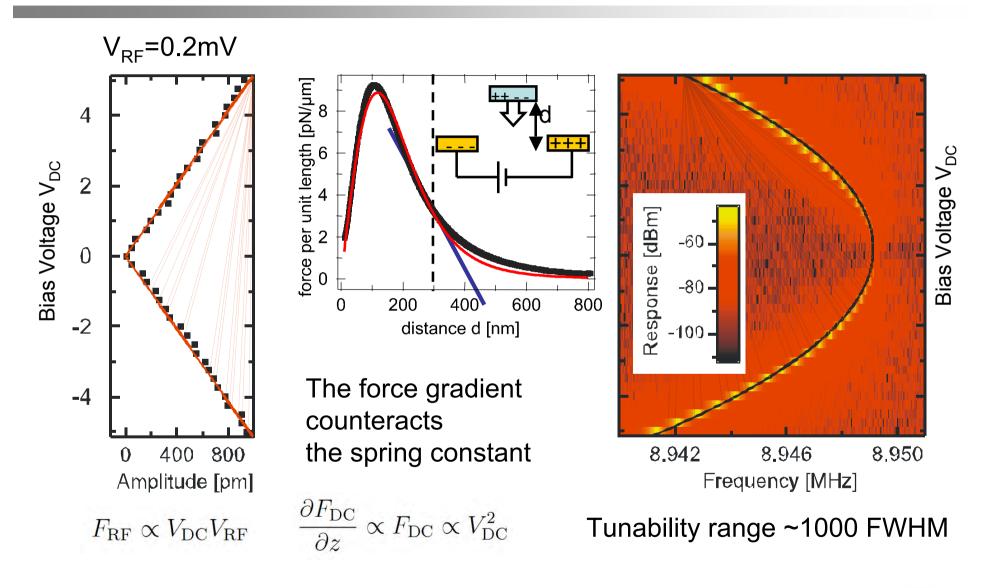


The principle of dielectric actuation





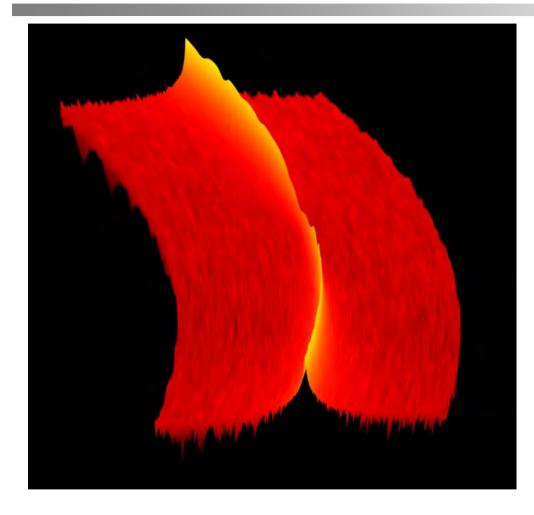
Dielectric actuation with interferometric detection





Dielectric actuation of nanomechanical resonators

Combining the advantages of local and external actuation



- + local, all-electronic, i.e. integrable
- + applicable to most materials (Q = 100,000 150,000)
- + polarization control via V_{DC}
- + efficient ($V_{RF} > 5 \mu V$)
- + scalable to high frequencies $R = 50 \Omega$ $C_{mutual} = 1.5 \, \text{fF}$

$$\Rightarrow f_{\text{cutoff}} = 1/(2\pi RC_{\text{mutual}}) \approx 2THz$$

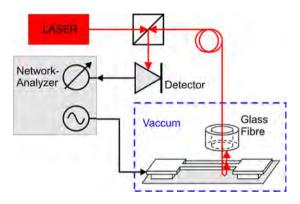
+ frequency tuning ~ V_{DC}^2 amplitude tuning ~ V_{DC}

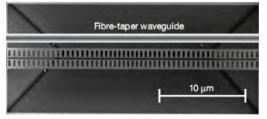
Q. Unterreithmeier, E. M. Weig, J. P. Kotthaus, Nature 458, 1001 (2009).

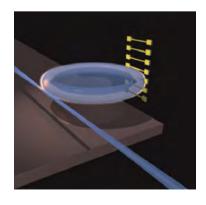


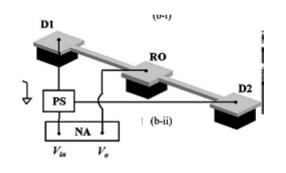
Towards scalable on-chip detection

Representative presently employed detection schemesOpticalElectrical

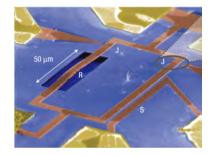




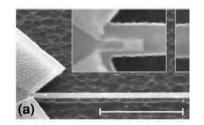


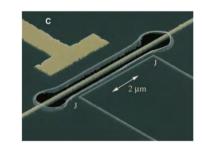


Magnetomotive



Flux-modulation





Piezoresistive

Single ElectronTransistor

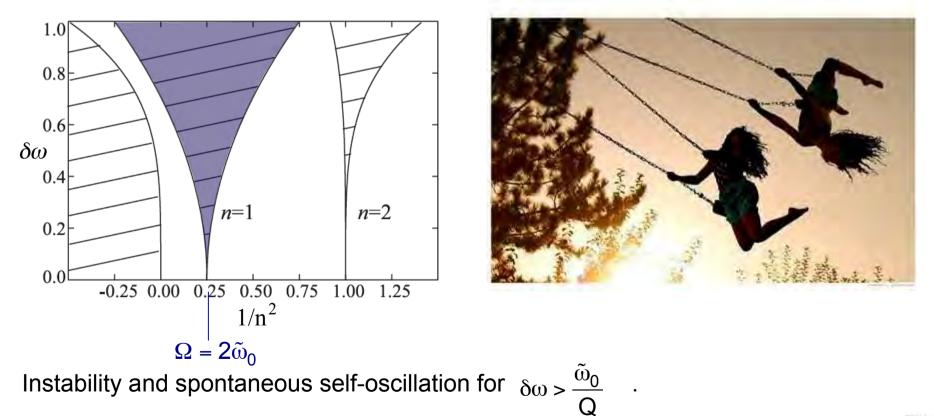


Parametric actuation

Self-oscillation without externally applied driving force

Modulate resonance frequency of the resonator at twice the resonance frequency:

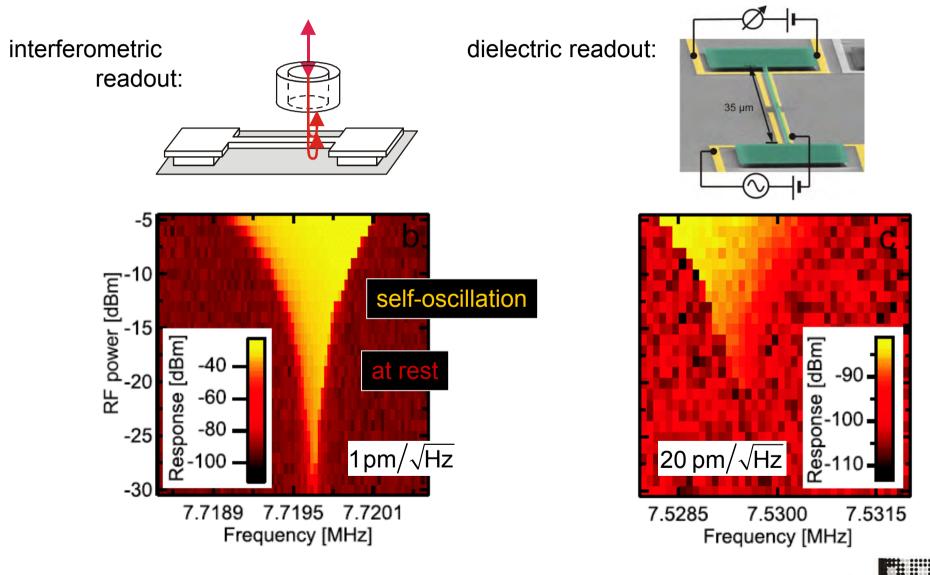
$$\frac{\partial^2}{\partial t^2}u[x] + \frac{\omega_0}{Q}\frac{\partial}{\partial t}u[x] + \omega_0^2(1 + \delta\sin(2\omega t))u[x] = 0$$



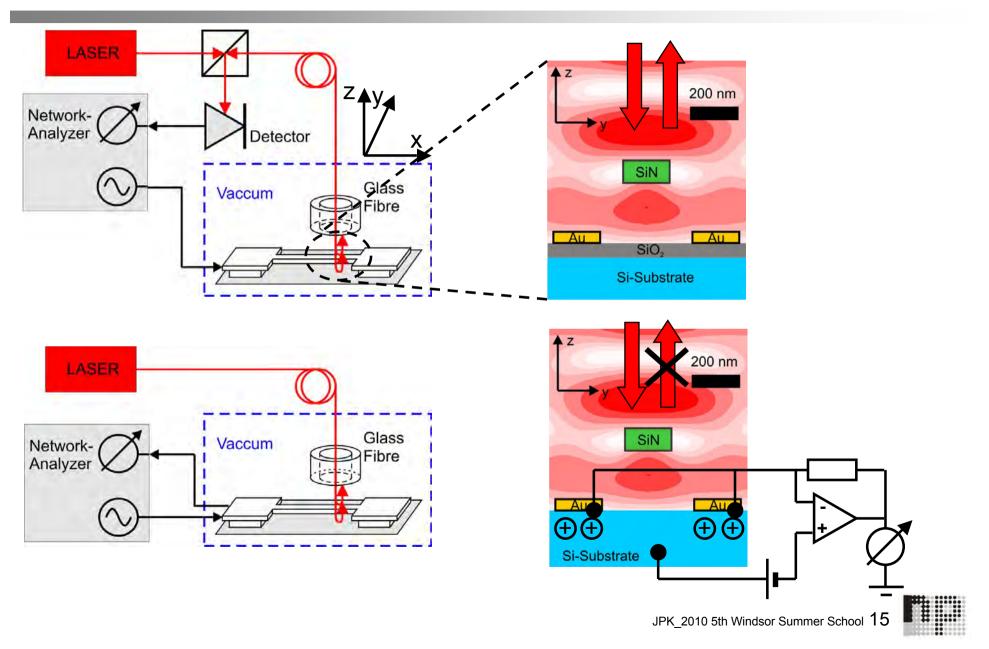


Parametric actuation and dielectric detection

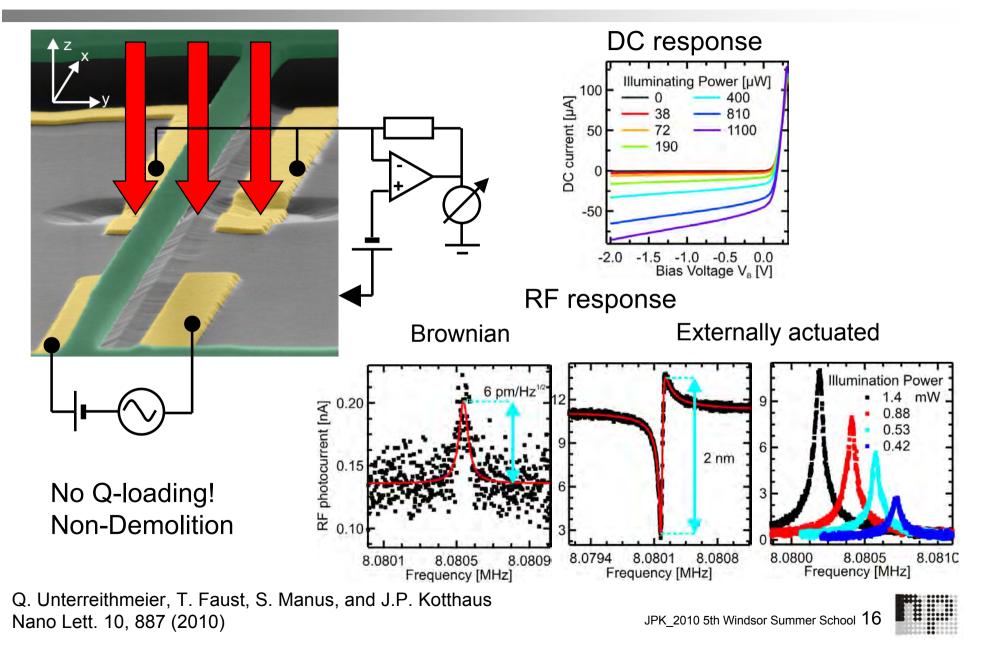
Modulating the resonance frequency at $2f_0$ via "V_{DC}" allows to invert the actuation principle

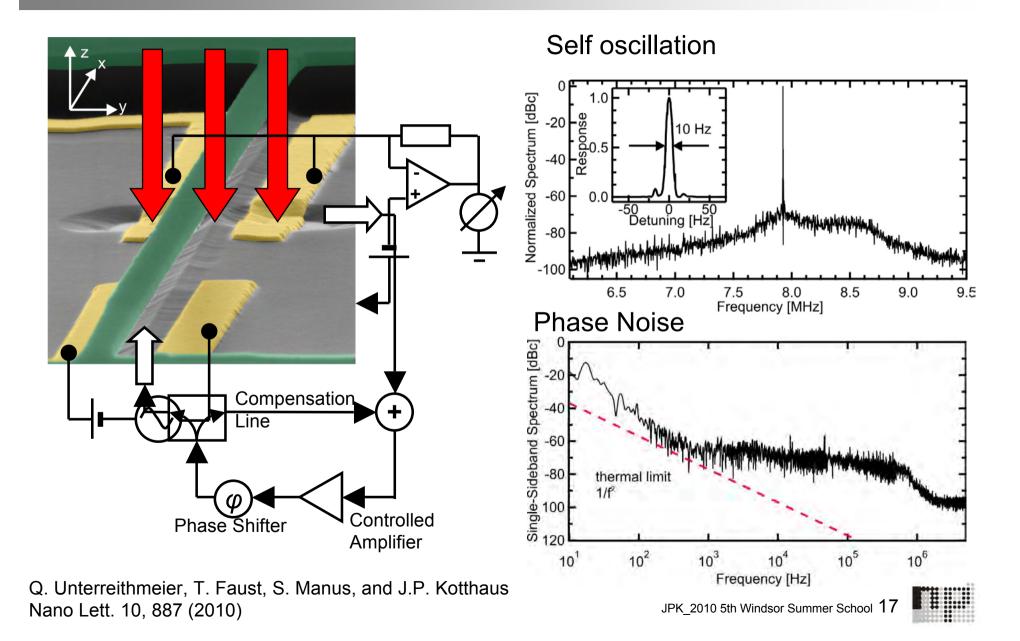


Concept of on-chip interferometric detection



On-chip interferometric detection with Schottky photodiode



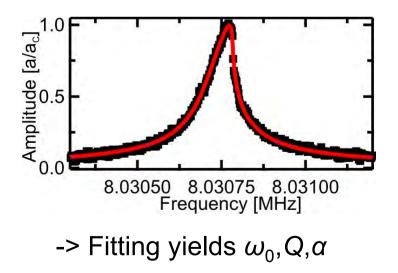


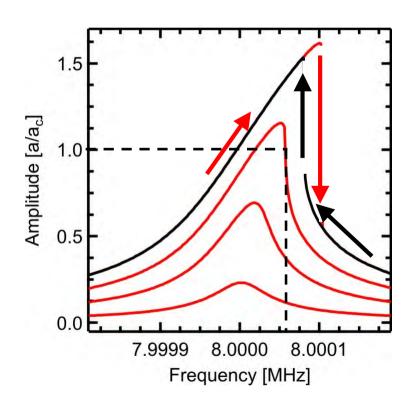
Non-linear nanomechanical oscillators - quasistatic behavior

$$\frac{\partial^2}{\partial t^2} u[x] + \frac{\omega_0}{Q} \frac{\partial}{\partial t} u[x] + \omega_0^2 (1 + \alpha u[x]^2) u[x] = \frac{F}{m} \cos[\omega t]$$

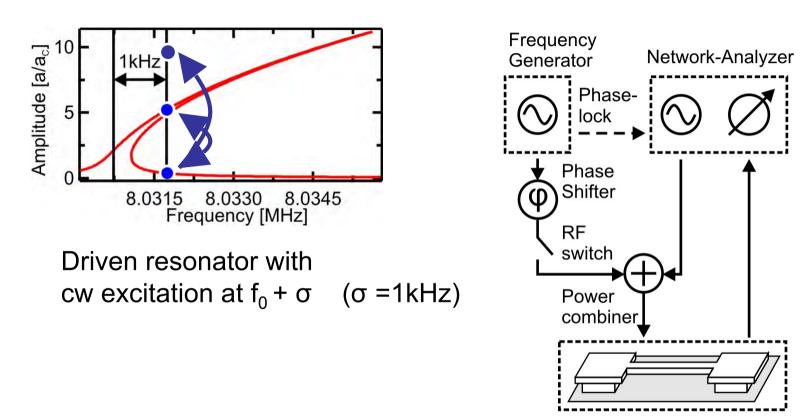
Equation of motion of a Duffing oscillator

$$u = a[\omega] \cos[\omega t + \gamma[\omega]]$$





Nonlinear nanomechanics - dynamical behavior



Fast switchable memory element employing short resonant RF-pulses?

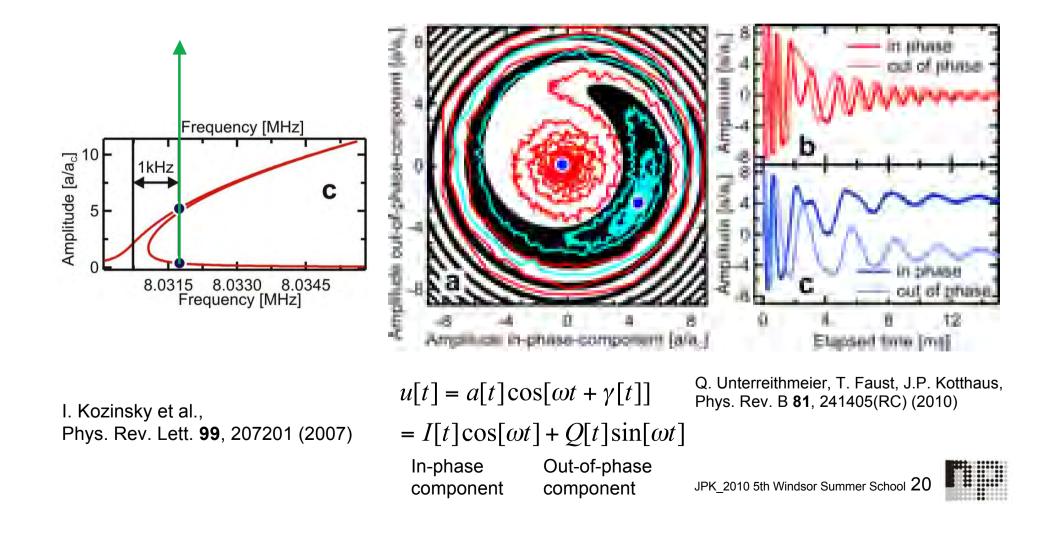
R. L. Badzey et al., Appl. Phys. Lett., **85**, 3587 (2004)

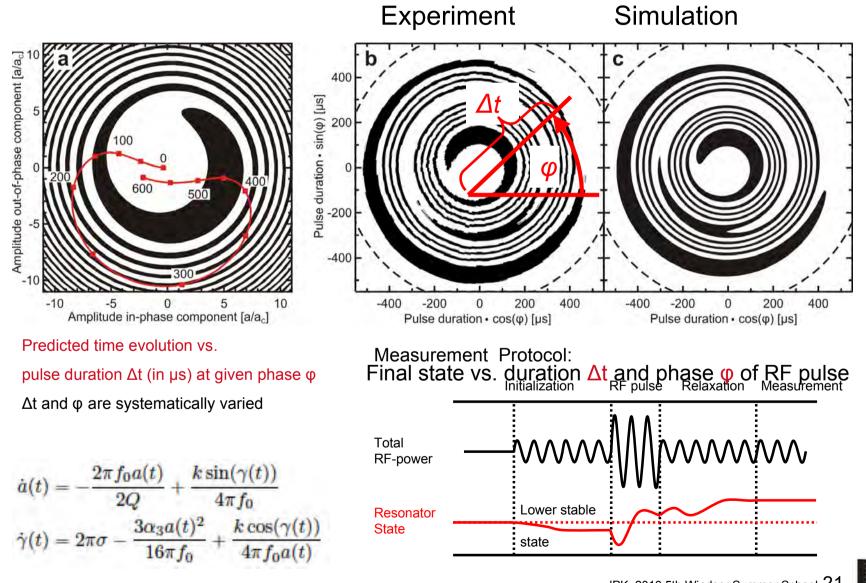
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Nonlinear dynamics - relaxation into basins of attraction

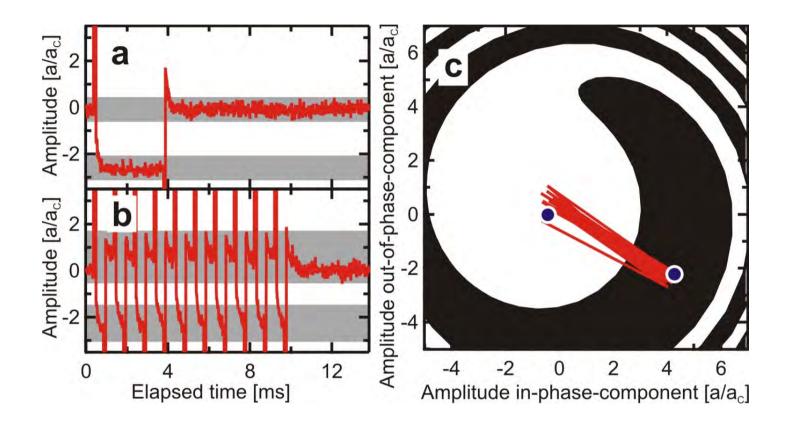
Relaxation of the resonator driven continuously at frequency $f_0 + \sigma$ after excitation with strong rf pulse (~ 250 µs long, 18 x cw-amplitude) of same frequency with amplitude a(t) and phase $\gamma(t)$







A non-adiabatically driven NEMS switch on route to a NEMS memory



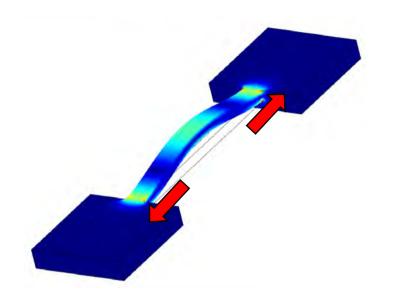
pulse duration 80 µs and repetition rate 1kHz, resonator relaxation time ~ 10 ms

-> switching beyond relaxation (10³ speed improvement)

Q. Unterreithmeier, T. Faust, J.P. Kotthaus, Phys. Rev. B **81**, 241405(RC) (2010)

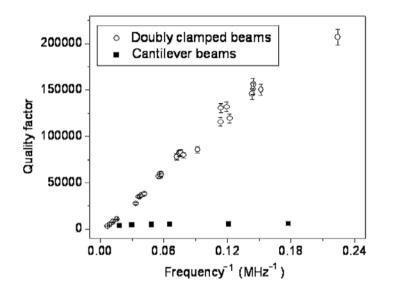


Damping: Quality factors of highly stressed beams



Mechanical quality factor

 $Q = 2\pi \frac{\text{energy stored}}{\text{energy loss per oscillation}}$



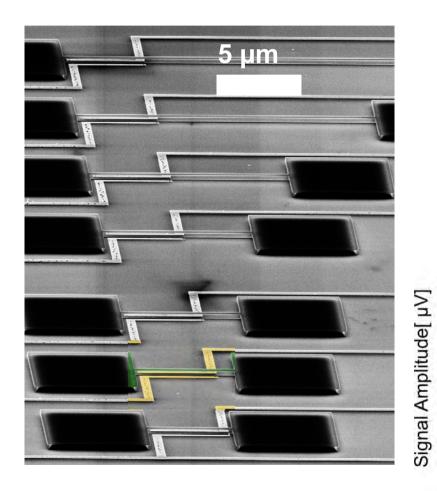
-> Stress increases Q

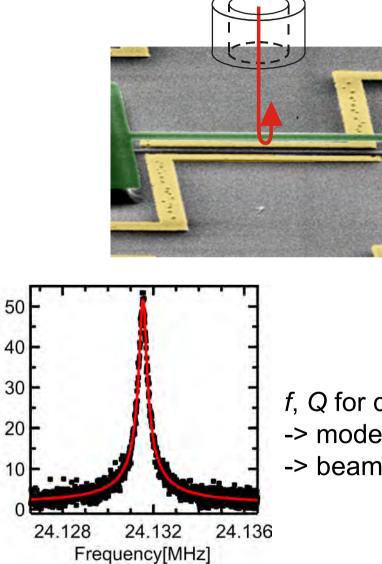
S. Verbridge et al., J. Appl. Phys. **99**, 124304 (2006)

Mechanism?



Exploring length and mode-dependence of Q-factor



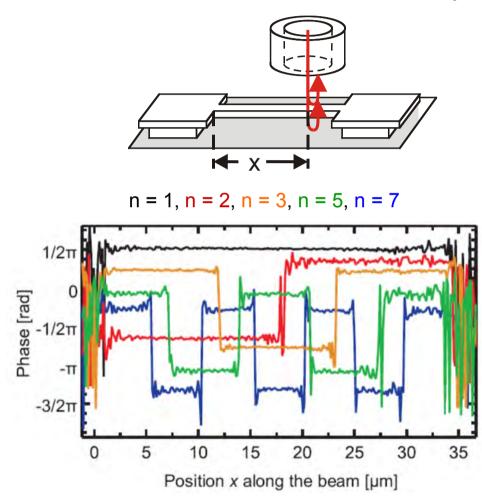


f, *Q* for different -> mode number -> beam length



Exploring frequency scaling and damping of harmonics

Each node of a vibrational modes yields a phase reversal:

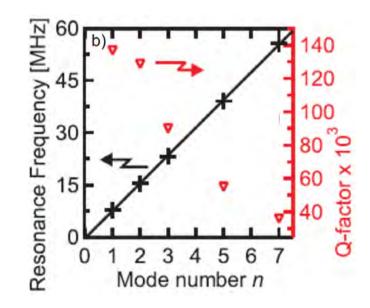


Q. Unterreithmeier, S. Manus, J. P. Kotthaus, Appl. Phys. Lett. 94, 263104 (2009)

• Bending rigidity: $f \alpha n^2$

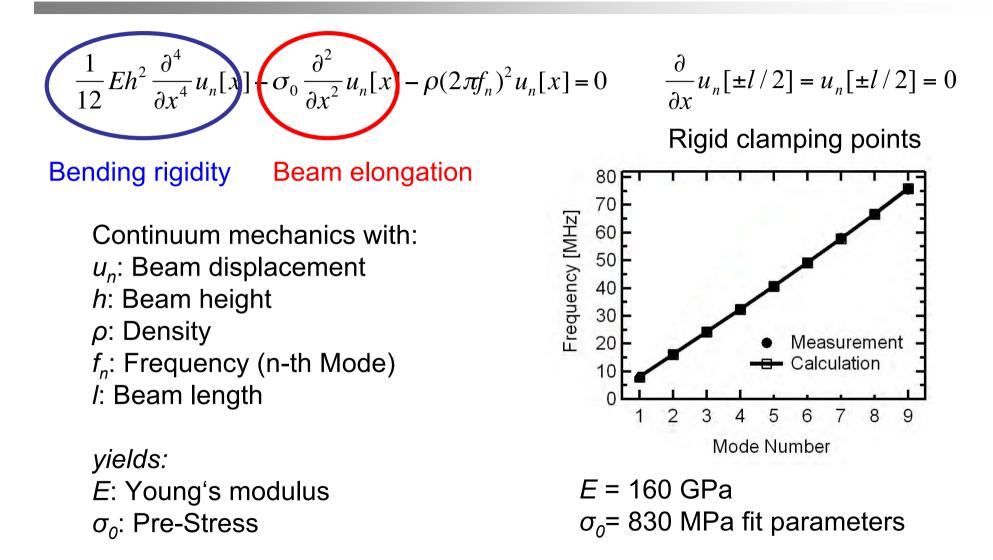








Resonance frequency versus harmonic mode



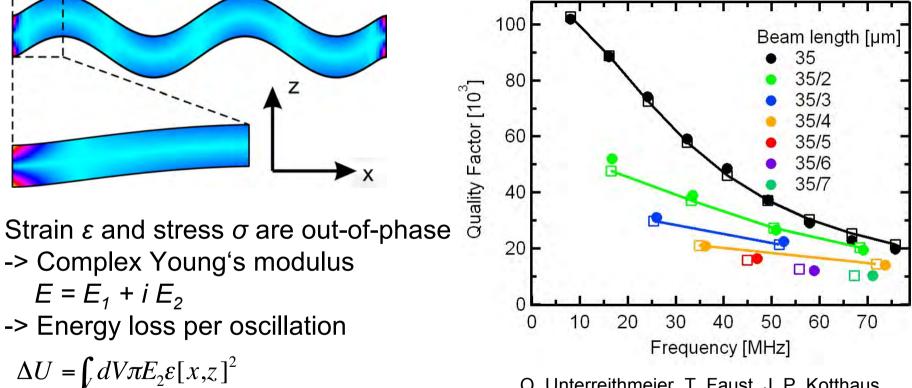


A simple single parameter damping model

consistent with experimental findings

Strain caused by displacement

Assumption: E_2 independent of x, mode, length



Q. Unterreithmeier, T. Faust, J. P. Kotthaus, Phys. Rev. Lett. 105, 027205 (2010)

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Unstressed Beam

$$U = \int dV \frac{1}{2} E_1 \varepsilon [x,z]^2$$

$$\Delta U = \int dV \pi E_2 \varepsilon [x,z]^2 \quad Q = \frac{\operatorname{Re}(E)}{\operatorname{Im}(E)}$$

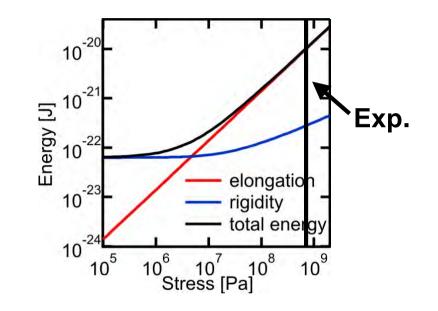
-> mode-independent Q

Stressed Beam

-> rigidity -> Young's modulus-> elongation -> external stress

$$U_{\text{elongation}} = \frac{1}{2} \sigma_0 w h \int_l dx (\partial / (\partial x) u[x])^2$$
$$U_{\text{rigidity}} = \frac{1}{24} E_1 w h^3 \int_l dx (\partial^2 / (\partial x)^2 u[x])^2 \propto \Delta U$$

Q. Unterreithmeier, T. Faust, J. P. Kotthaus, Phys. Rev. Lett. 105, 027205 (2010)



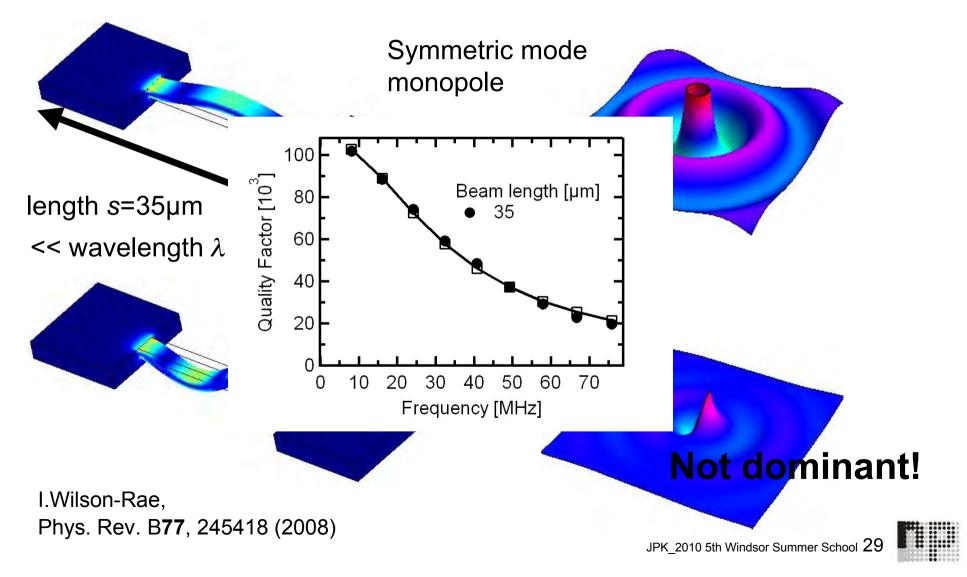
-> stress increases stored energy
-> stress does not change local
energy loss very much

-> higher mechanical Q dominated by increased stored energy and not by reduced damping

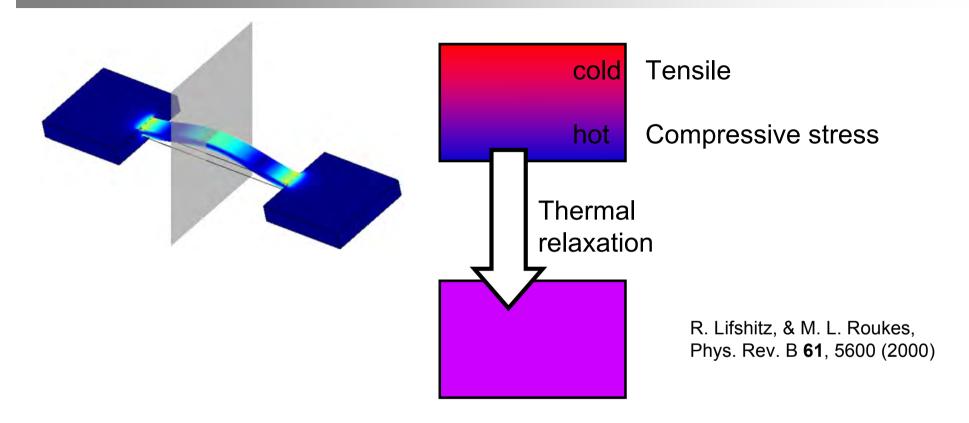


Contribution of clamping losses to damping

Irradiation of acoustic waves into the substrate



Contribution of thermoeleastic damping

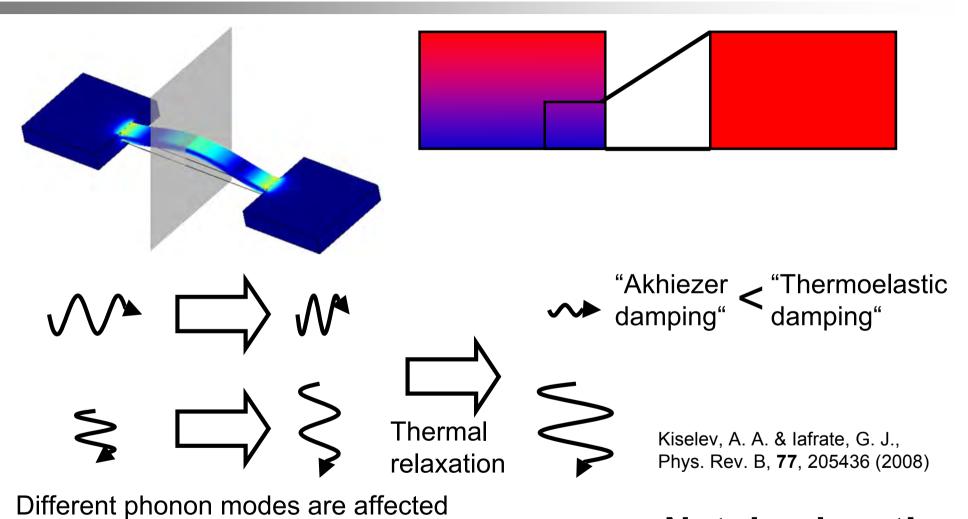


-> Very small damping-> Thermal relaxation faster than oscillation (-> frequency dependence)

Not dominant!



Contribution of the Akhiezer effect to damping



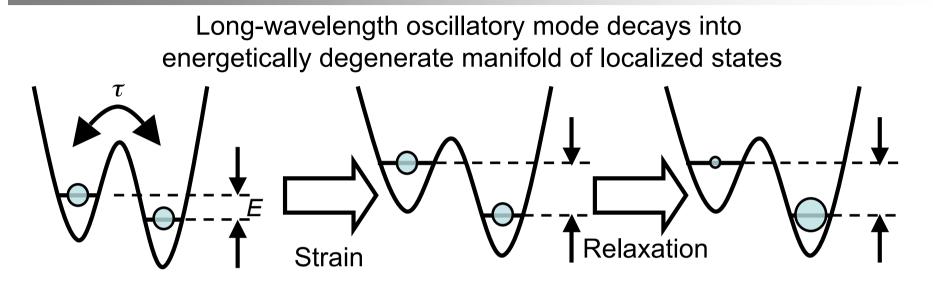
differently by strain

-> each mode has different temperature

Not dominant!



Damping via localized defect states



broad distribution in $E_{,\tau}$ high temperature limit -> frequency independent

energy loss

J. Jaeckle, Z. Phys. 257, 212 (1972)

Magnitude well in the "glassy range" at "medium temperature"

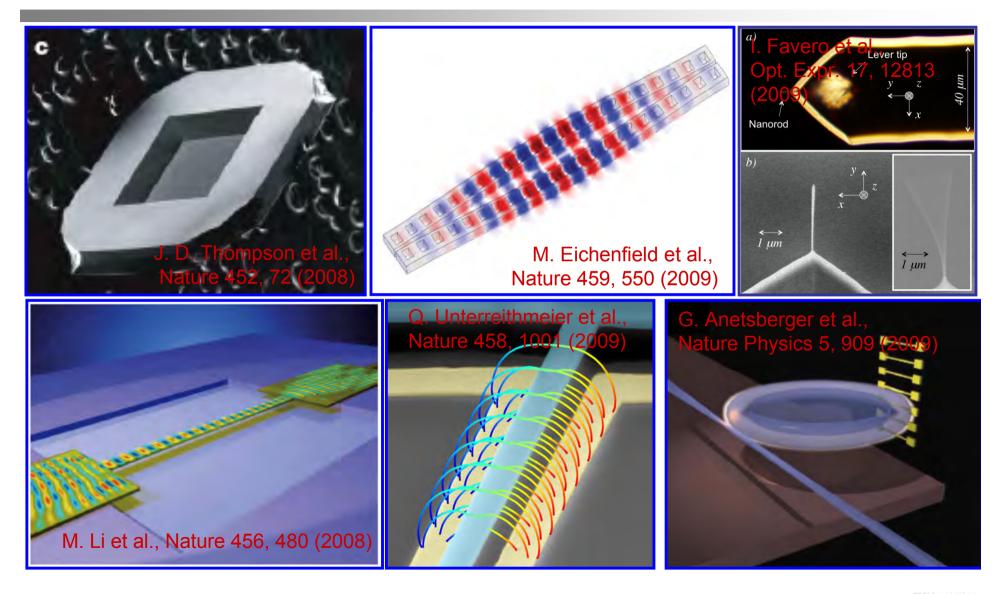
Most likely!

D. R. Southworth et al., Phys. Rev. Lett., **102**, 225503 (2009) R. Pohl, et al. Rev. Mod. Phys., **74**, 991 (2002)



Gradient forces in NanoOptoMechanical Systems

Recent examples of actuation, transduction and back-action





Cavity - Nanomechanics via optical gradient forces



The Kippenberg team: Georg Anetsberger, Oliver Arizet et al.



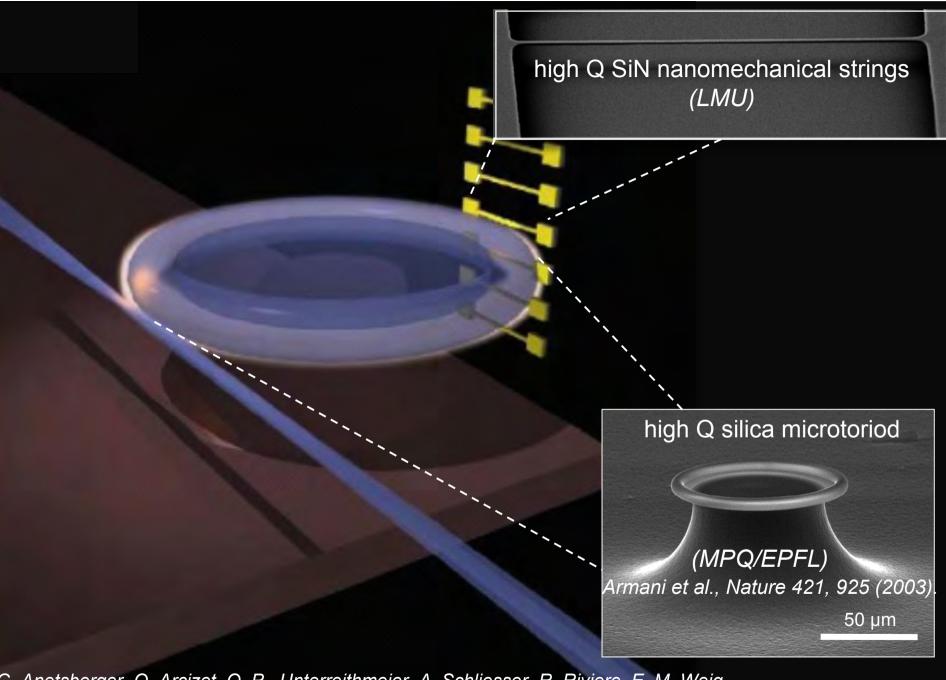
The Kotthaus team: Quirin Unterreithmeier, Eva Weig et al.



LUDWIG-MAXIMILIANS-UNIVERSITÄT MÜNCHEN

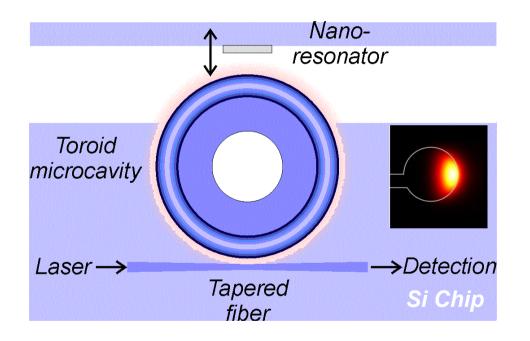






G. Anetsberger, O. Arcizet, Q. P. Unterreithmeier, A. Schliesser, R. Riviere, E. M. Weig, J. P. Kotthaus, T. J. Kippenberg, Nature Physics **5**, 909 (2009)

Concept Achieve sub-wavelength resolution using optical near-fields



Challenges:

Microfabrication:

- "edge cavities"

Positioning:

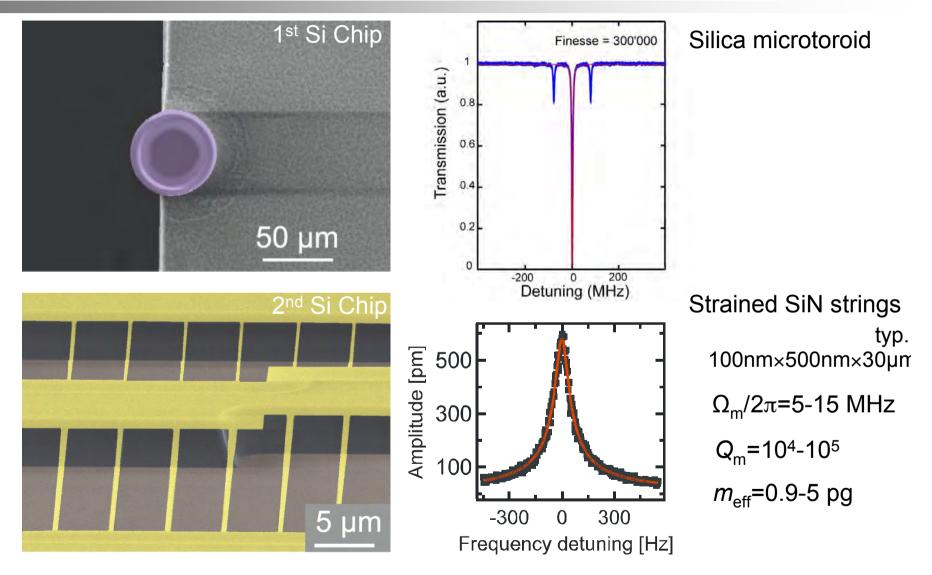
- alignment of nanoresonator chip parallel to chip <0.5°
- nanopositioning of fiber *and* resonator
- optical imaging

Absorption?



Fabrication of high Q optical and mechanical resonators

Independent fabrication of cavity and resonator on two separate chips

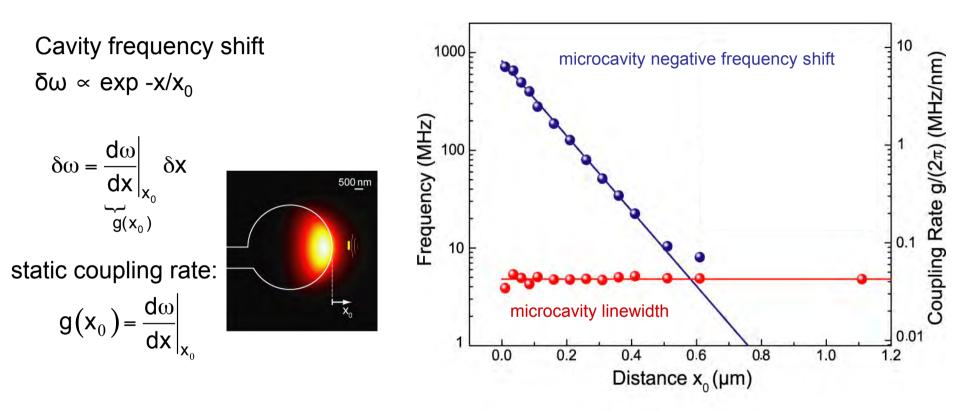




Static optomechanical coupling vs. distance

Interaction with the resonator induces a static shift in cavity frequency

Approaching the resonator in the toroid plane

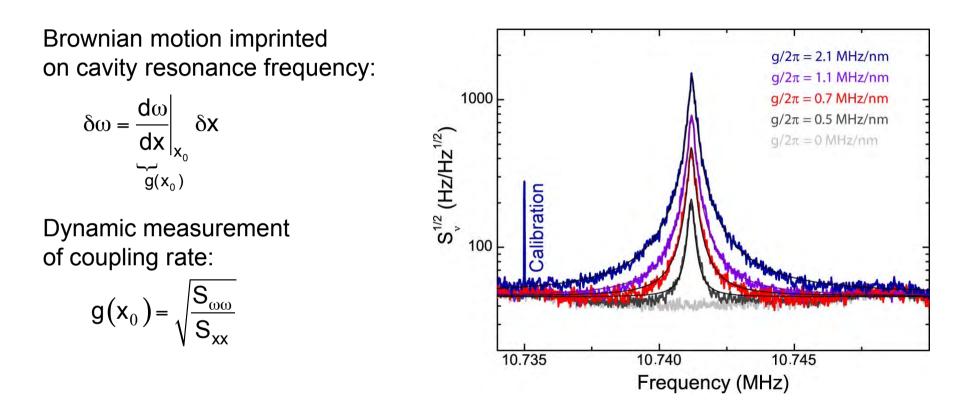


- \Rightarrow purely dispersive coupling
- \Rightarrow optomechanical coupling rate g/(2 π) up to 10 MHz/nm

frequency shifts up to 1 GHz obtained without degrading optical finesse

Dynamic optomechanical coupling

Transduction of Brownian motion of the resonator into cavity frequency noise

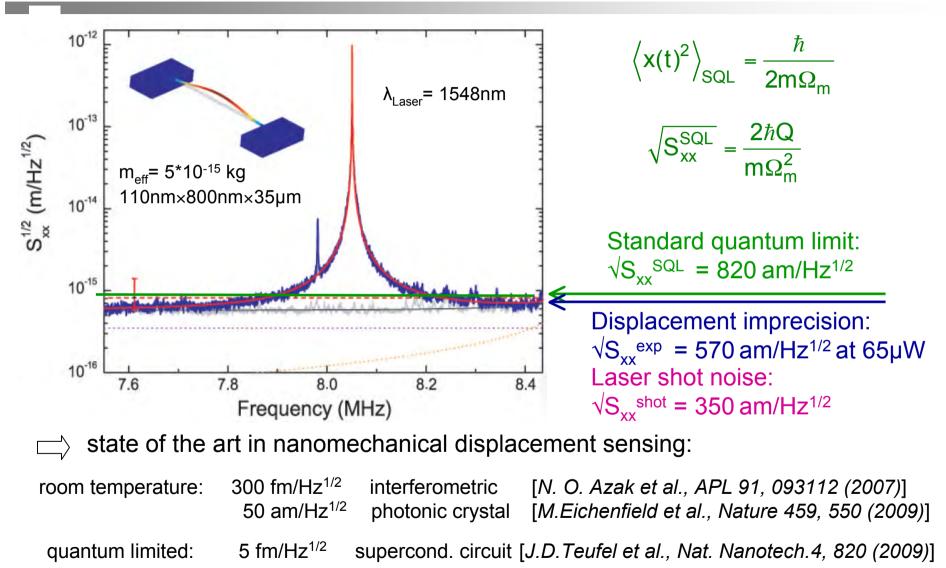


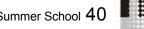
- \Rightarrow good agreement with statically determined values
- \Rightarrow dispersive coupling with optomechanical coupling rate g/(2 π) up to 10 MHz/nm

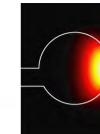


Quantum limited displacement sensitivity

with sub-femtometer resolution of a nanomechanical resonator at room temperature

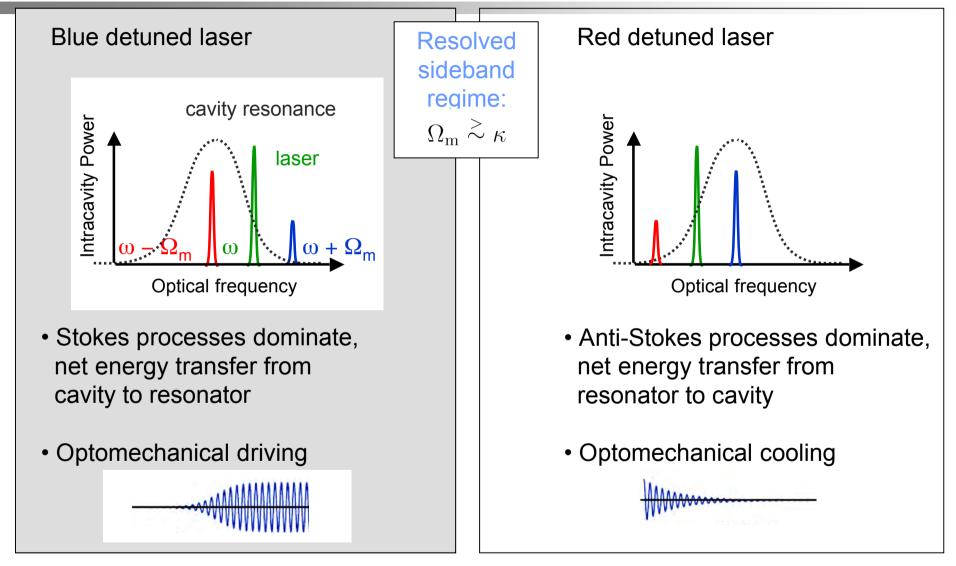






Dynamical back action on nanomechanical resonators

via the radiation-pressure-induced optical dipole force





Dynamical back action on the nanomechanical resonator

Radiation-pressure-induced coherent self-oscillation

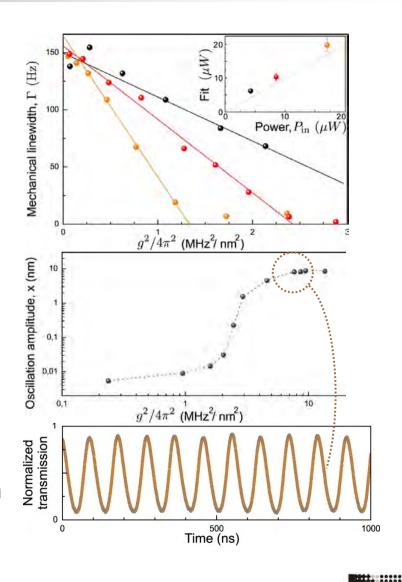
Linewidth narrowing:

• Net energy increase corresponds to reduced damping

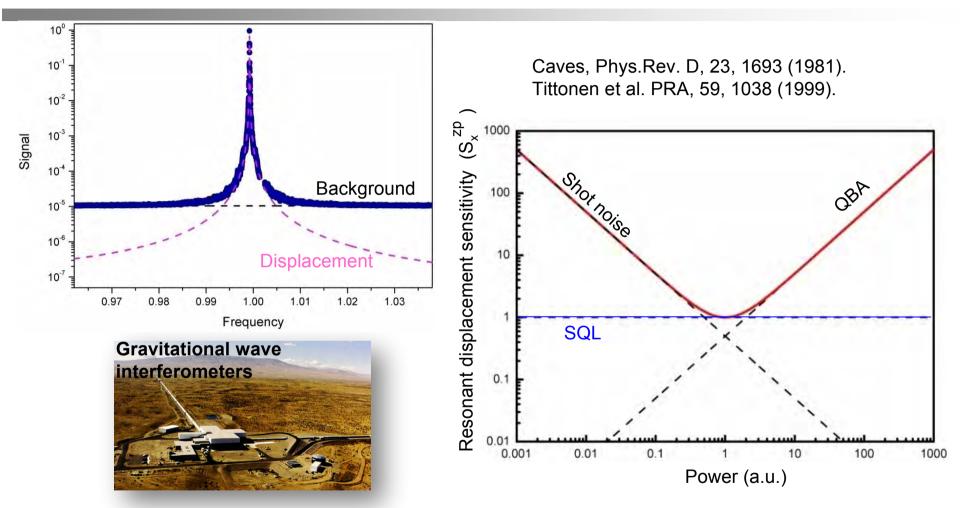
$$\Gamma = \Gamma_{\rm m} + \Gamma_{\rm ba}$$
 with $\Gamma_{\rm ba} \propto -g^2 \cdot P_{\rm in}$

Oscillation threshold and saturation: • Zero damping at threshold

Coherent oscillation: • Radiation pressure induced self-oscillation



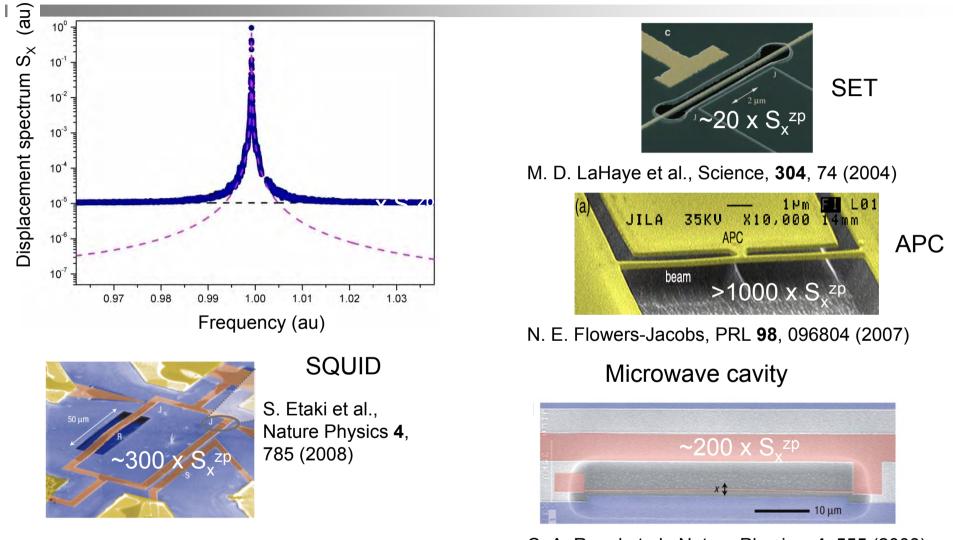
Quantum limits for continuous position measurement



- So far only transducers based on optical cavities are close to shot-noise limit
- Not directly applicable to nanomechanical oscillators due to diffraction



Recent transducers sensitivities for nanomechanical motion



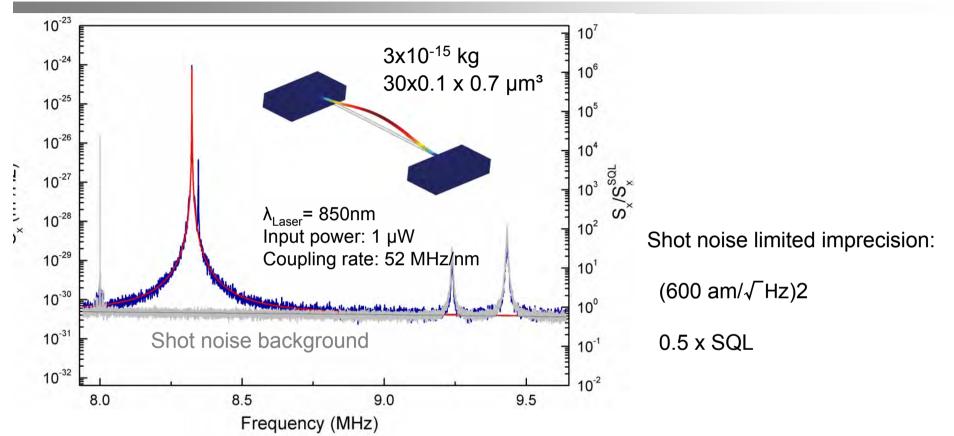
C. A. Regal et al., Nature Physics, 4, 555 (2008)



Imprecision larger than zero-point motion

ľ

Imprecision below the SQL

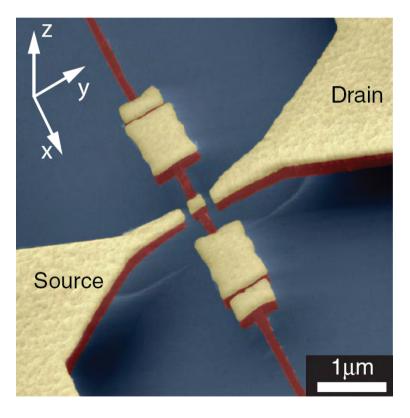


300 K optical measurement of displacement with an imprecision of 0.5xSQL, expected to go below 0.1xSQL at T< 30K, as limited by thermorefractive noise at 300 K G. Anetsberger et al., submitted

Optically achieved 300 K-value comparable to imprecision of 0.4'SQL recently **Upensity explored any ity Back action Kand back-action evading techniques** J. D. Teufel et al., Nature Nanotechnology 4, 820 (2009)



Nanomechanical charge transport



in collaboration with Daniel König and Eva Maria Weig

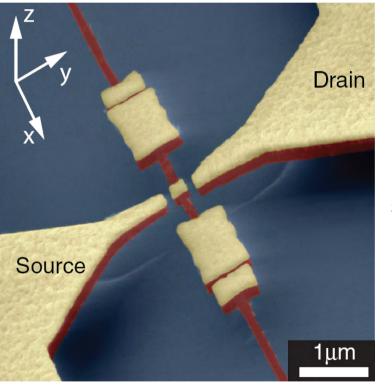




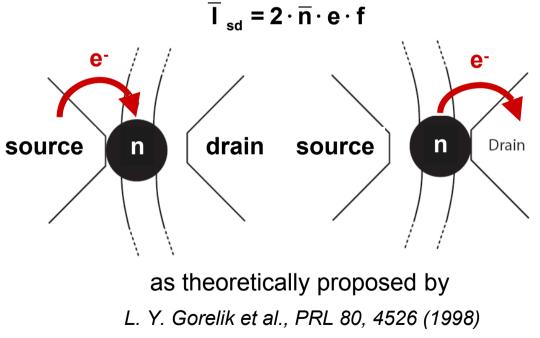


A Nanomechanical charge shuttle

The concept of nanomechanical (single) electron transport



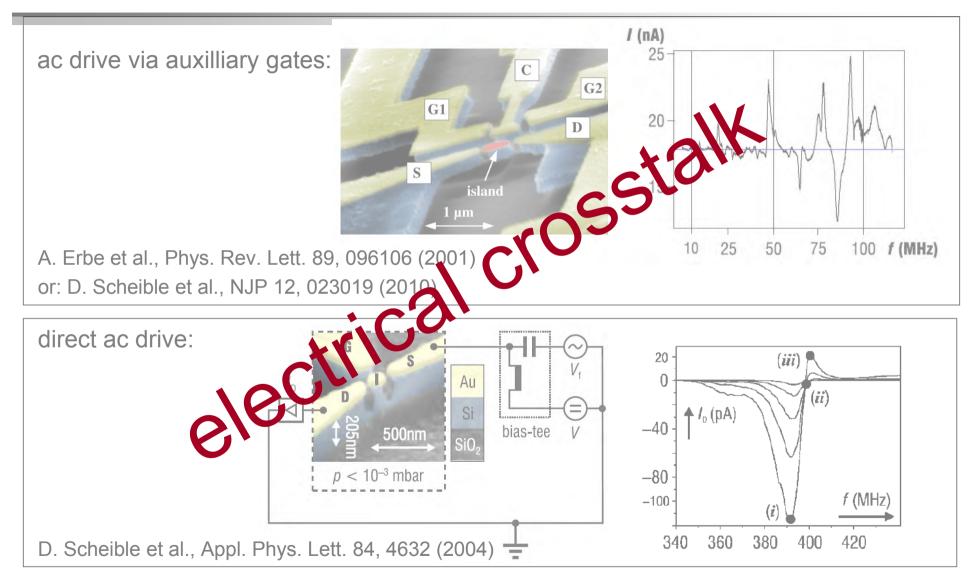
Mechanical actuation of an electrical current:





A short history of shuttles

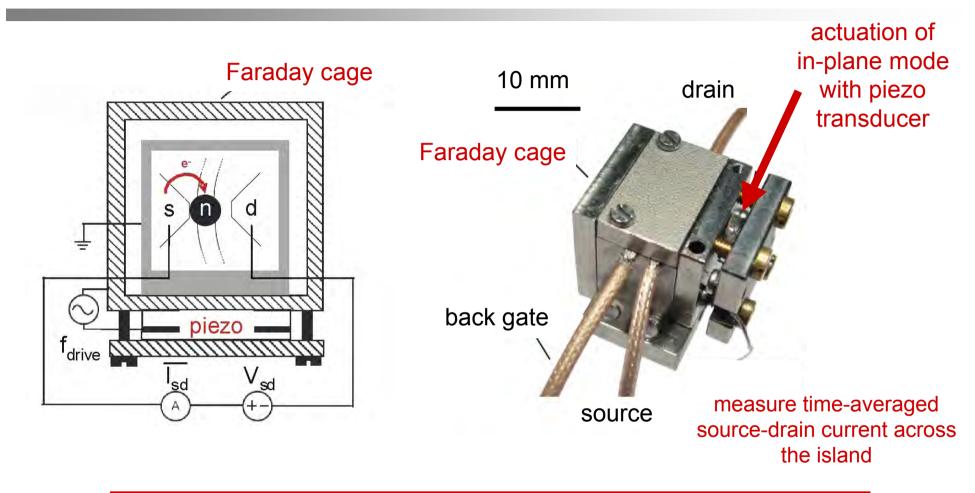
The quest of finding the right actuation mechanism to enter the Coulomb blockade regime





Inertial actuation of the shuttle

using acoustic waves produced by a piezo transducer shielded by a Faraday cage

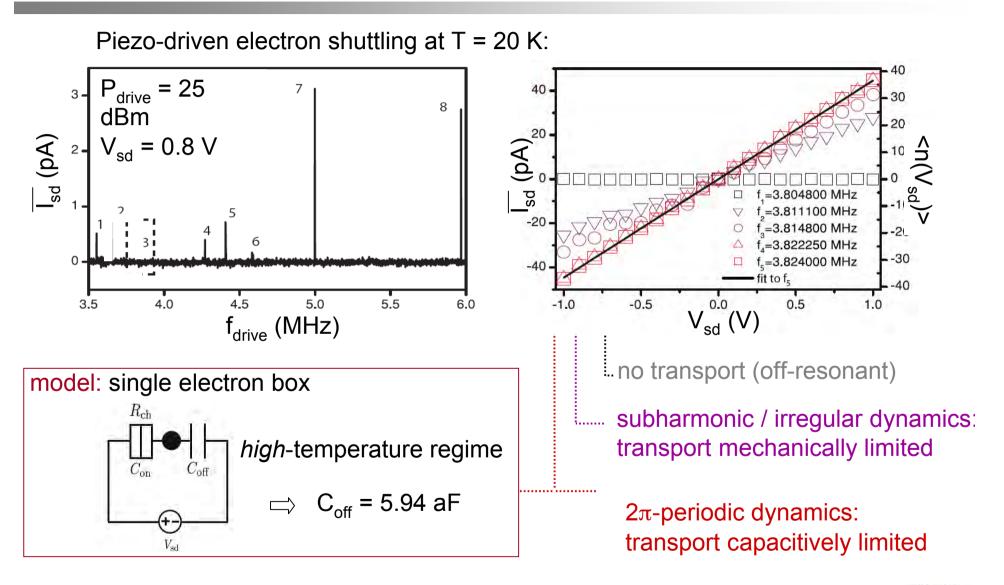


Faraday cage ensures complete decoupling from the drive signal

König, Weig, Kotthaus, Nature Nanotechnology 3, 482 (2008)



Transport characterization of individual shuttles Not all shuttles display stable mechanical trajectories giving rise to charge transport

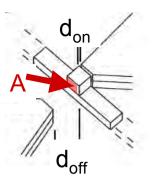


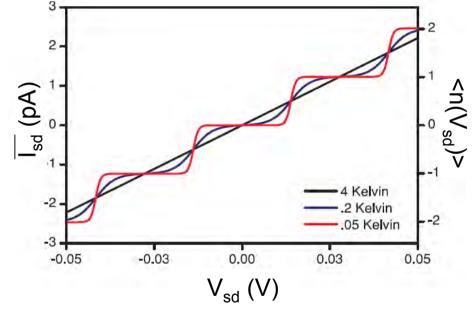


A mechanical *single* electron shuttle?

Prerequisites for entering the Coulomb blockade regime

island cross section area A = 140 nm x 60 nm

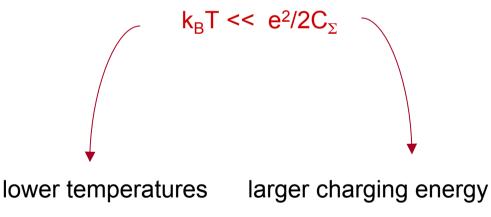




Coulomb blockade at 200 mK

"Coulomb blockade"

fixed electron number on the island: thermal energy must not exceed the charging energy

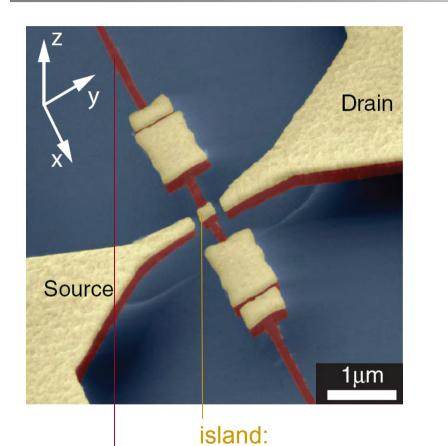


non-dissipative actuation scheme

smaller island

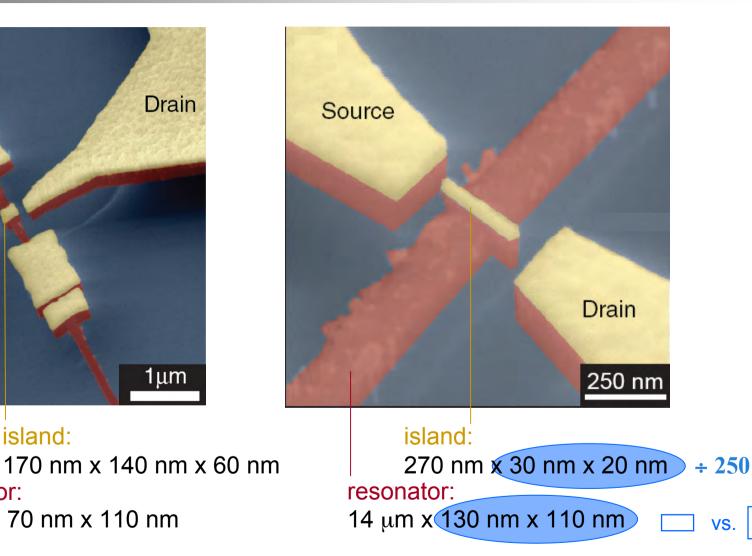


Nanomechanical charge shuttle The concept of nanomechanical (single) electron transport



14 μ m x 70 nm x 110 nm

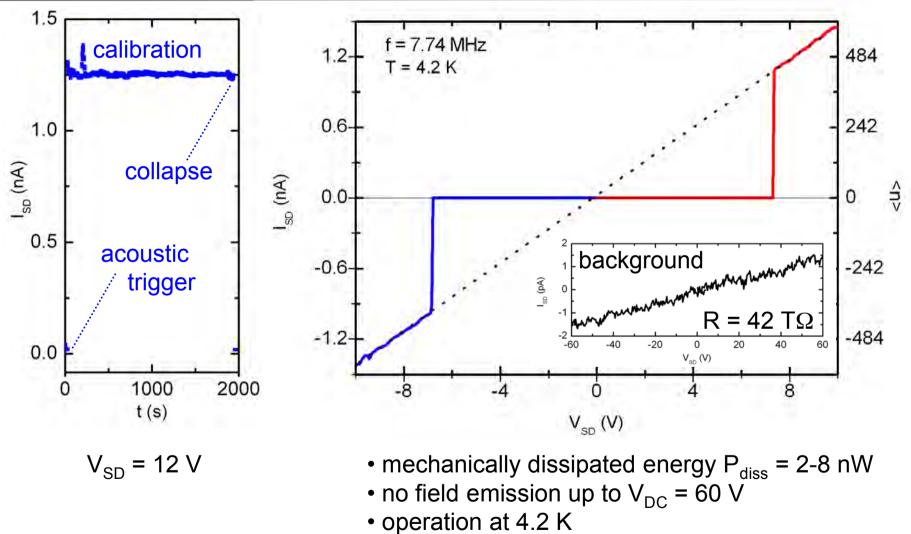
resonator:



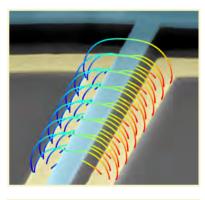


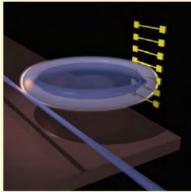
Voltage-induced self-oscillation

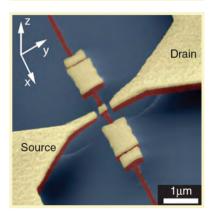
Self-sustained shuttling for bias voltage exceeding shuttle dissipation threshold



SUMMARY







Transduction via dielectric gradient fields

- External yet local actuation of dielectric resonators
- Integrated optoelectronic detection
- Control of linear and nep-linear sparning
- High Q I S C S I Eschator understood
- Progress towards an understanding of damping
- On route to scalable and efficient or clip P 2/5

Near-field cavit hard-up omechanics

- to the hanoscale
- Dynamical back action on nanomechanical oscillators
- Imprecision of motion detection at 300K below SQL

Nanomechanical charge shuttle

- Capacitance controlled electron shuttling demonstrated
- Self-oscillation observed
- Approaching Coulomb blockade regime

